



**PATENT APPLICATION**

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of

Yasuhiro OMURA et al.

Group Art Unit: 2873

Application No.: 10/525,372

Examiner: M. HASAN

Filed: February 23, 2005

Docket No.: 122800

For: PROJECTION OPTICAL SYSTEM AND METHOD FOR PHOTOLITHOGRAPHY  
AND EXPOSURE APPARATUS AND METHOD USING SAME

**AMENDMENT**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

In reply to the May 19, 2006 Office Action, the shortened statutory period for reply  
being extended by the attached Petition for Extension of Time, please consider the following:

**Amendments to the Claims** as reflected in the listing of claims; and

**Remarks.**